

Internal Seminar

Developing in-house capability to fabricate vertical magnetic junction device

Mathimalar S

TCIS, Hyderabad

In this talk, I will present the importance of an integrated thin film cluster system in which thin film devices can be fabricated at ultra-high vacuum conditions (not atmosphere!). I will also talk about the TMR device stacks fabricated and the initial magnetic characterizations performed on the above samples. I will explain the significance of in-situ shadow mask in making thin film vertical junction devices and describe details of the Cu shadow mask made using photo lithography technique. In the end, I will conclude with the future work plan.

Friday, Sep 2nd 2016

10:00 AM (Tea/Coffee at 9:45 AM)

Seminar Hall, TCIS